

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Tamotsu OWADA et al.**

Serial Number: **Not Yet Assigned**

Filed: **October 29, 2003**

Customer No.: 38834

For: **SILICON OXYCARBIDE, GROWTH METHOD OF SILICON OXYCARBIDE
LAYER, SEMICONDUCTOR DEVICE AND MANUFACTURE METHOD FOR
SEMICONDUCTOR DEVICE**

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

October 29, 2003

Sir:

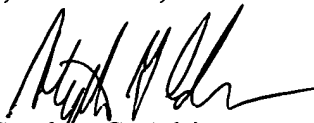
In compliance with 37 CFR 1.56, Applicants call to the attention of the Patent and Trademark Office the references listed on the attached PTO-1449.

A copy of the reference is enclosed herewith, except for the U.S. reference.

In the event there are any fees due in connection with the filing of this paper, please charge

Deposit Account No. 50-2866.

Respectfully submitted,
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Enclosures: PTO-1449; Reference (1)

INFORMATION DISCLOSURE STATEMENT PTO-1449	Atty. Docket No. 032060	Serial No. New Appln.
	Applicant(s): Tamotsu OWADA et al.	
	Filing Date: October 29, 2003	Group Art Unit:

U.S. PATENT DOCUMENTS

Examiner Initial		Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
_____	AA	2003/0134505	Dalton et al.	07/17/03			
_____	AB						
_____	AC						
_____	AD						

FOREIGN PATENT DOCUMENTS

		Document No.	Date	Country	Translation (Yes or No)
_____	AE	2003-218109	07/31/03	Japan	No. Discussed in the specification.
_____	AF				
_____	AG				
_____	AH				
_____	AI				

OTHER DOCUMENTS

_____	AJ	
_____	AK	

Examiner	Date Considered
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